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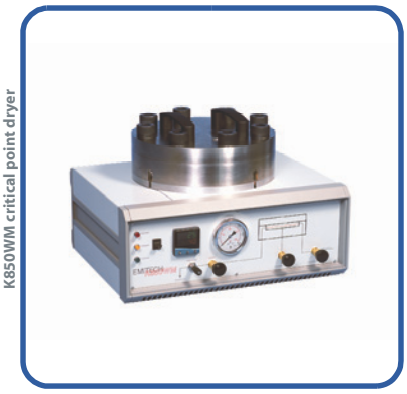
CRITICAL POINT DRYER

K850WM Large Chamber (MEMS) Critical Point Dryer

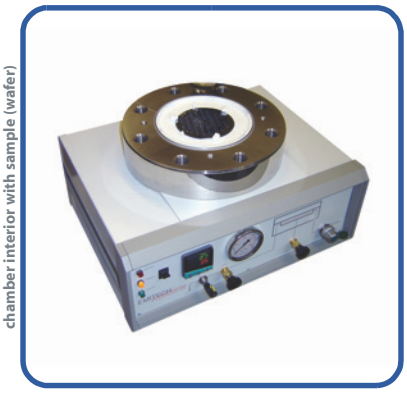
larger chamber critical point dryer for wafers and MEMS

EMITECH sample preparation

cost effective dryer for MEMS/wafers



K850WM critical point dryer



chamber interior with sample (wafer)

K850WM Critical Point Dryer
The K850WM is designed to critical point dry a complete 150mm (6") wafer. The K850WM is fitted with thermo-electronic heating and adiabatic cooling and temperature control of +5˚C cooling and +35˚C during heating. This ensures the critical point is accurately obtained, avoiding excess pressures or temperatures, or the need to rely on pressure relief valves to control pressure during the heating cycle. The K850WM has a vertical chamber which allows top loading of specimens. A viewing port is fitted in the top plate for sample observation. The K850WM sample exchange mechanism is simple to use and ensures the sample remains under liquid during loading.

Sample handling
100mm or 150mm diameter wafers are held in a PTFE holding tray. The tray including wafer is immersed in acetone in order to remove all moisture from the sample. After dehydration, the wafer and holder is transferred into the pre-cooled sample chamber using the wafer transfer device. On completion of the critical point drying process, the wafer is removed from the chamber using the transfer device prior to further processing.

Key Features & Benefits
- 170mm diameter chamber - optimised for wafer / MEMS drying
- Vertical chamber with top filling and bottom draining - ensures specimens do not become uncovered during drying
- Thermoelectric heating - accurate temperature control
- Fine control needle valve pressure let down - precise control
- Temperature monitoring and control with thermal cut-out protection
- Pressure monitoring with safety cut-out for over pressure

Requirements
E4860 Heater/chiller (for cooling chamber)
EK3102 CO_2 bottle heating system

See: www.quorumtech.com for full technical specification and additional details.

PRODUCT SPECIFICATIONS

Supplied with	PTFE specimen holder (for a 150mm wafer), high pressure CO_2 hose, operating manual and test certificate
Chamber size	170mm internal diameter x 15mm high
Test pressure	3000psi
Operating temperature	Normal operating temperature 35˚C (critical temperature 32˚C)
Operating pressure	1350psi (critical pressure 1172psi)
Pressure safety cut-out	1700psi
Weights & dimensions	450mm W x 350mm D x 175mm H. Weight:12Kg
Site considerations	Requires space for CO_2 cylinder
Electrical	230V 50Hz (3A max) 115V 60Hz (6A max)